

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Yoshitaka Nishio et al.

Serial No.: to be assigned

Filed: herewith

For: METHOD FOR REMOVING DEPOSIT FROM SUBSTRATE  
AND METHOD FOR DRYING SUBSTRATE, AS WELL AS  
APPARATUS FOR REMOVING DEPOSIT FROM SUBSTRATE  
AND APPARATUS FOR DRYING SUBSTRATE USING THESE  
METHODS

ATTN: Application Division

**PRELIMINARY AMENDMENT**

Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Prior to examination on the merits of this application and prior to  
calculation of the filing fee, please amend the above-identified application as  
follows:

Amendments to the Claims; and

Remarks are included following the amendments.